

Docket Number: 081468-0306865
Client Reference: P-0393.010-US



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

LOWISCH et al.

Group Art Unit: 2812

Application No.: 10/716,939

Examiner: NOT ASSIGNED

Filed: November 20, 2003

Confirmation No.: 6805

For: DEVICE MANUFACTURING METHOD AND COMPUTER PROGRAM

May 4, 2004

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom. Applicants respectfully request the Examiner return an initialed copy of the enclosed Form PTO-1449 to Applicants with the next Office communication to indicate that the reference(s) has been considered, per MPEP § 609.

This Information Disclosure Statement is being filed before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

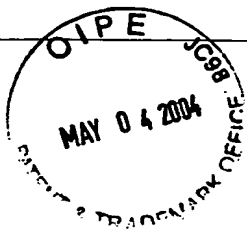
The references were cited in a counterpart foreign application. An English language version of the foreign search report is attached for the Examiner's information.

Respectfully submitted,

PILLSBURY WINTHROP LLP

Robert C. Perez
Reg. No. 39328

RCP/smm
P.O. Box 10500
McLean, VA 22102
Telephone: (703) 905-2000
Facsimile: (703) 905-2500
Customer Number: 00909



Atty.
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Client Ref.

306865

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**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

Applicant: LOWISCH et al.

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of

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Examiner: NOT ASSIGNED

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U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR						
	BR						
	CR						
	DR						
	ER						
	FR						
	GR						
	HR						
	IR						
	JR						
	KR						
	LR						
	MR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
						Enclosed	No	Enclose	No
	NR	1 271 247 A1	01/2003	EUROPE	Van der Werf et al.				
	OR								
	PR								
	QR								
	RR								
	SR								
	TR								
	UR								

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

	VR	Chen et al., "Simulation on a New Reflection Type Attenuated Phase Shifting Mask for Extreme Ultraviolet Lithography," <i>SPIE</i> , Vol. 3676, March 1999, pp. 578-586.			
	WR				
	XR				
	YR				
	ZR				
	AAR				

Examiner

Date Considered:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.